

Substitute for form 1449A/PTO

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

 ATTORNEY'S DKT NO.  
033033-002

 APPLICATION NO.  
09/889,956

APPLICANT

Hans-Joachim QUENZER et al.

FILING DATE

July 25, 2001

GROUP

Unassigned

## U.S. PATENT DOCUMENTS

Examiner Initials	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication (MM-DD-YYYY)
	Number	Kind Code (if known)		
CL	5,310,623	A	GAL	5/10/1994
↓	5,623,368	A	CALDERINI et al.	4/22/1997
↓	5,876,642	A	CALDERINI et al.	3/02/1999
↓	3,961,929		STOCKDALE	6/08/1976
↓	4,883,525		BUCKLEY et al.	11/28/1989
↓	4,883,524		BRISTOL	11/28/1989
CL	5,122,176	A	GOETTLER	6/16/1992

## FOREIGN PATENT DOCUMENTS

Examiner Initials	Foreign Patent Document		Country	Date of Publication (MM-DD-YYYY)	Translation	
	Number	Kind Code (if known)			Yes	no
CL	0 567 896	A1	EUROPE	11/03/1993		
↓	97/19027	A1	INTERNATIONAL	5/29/1997		
↓	0 690 028	A1	EUROPE	1/03/1996		
↓	0 493 202	A1	EUROPE	7/01/1992		
CL	1 596 490		GERMANY	5/19/1971		

## NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
CL	Dong QUIN et al., "Microfabrication, Microstructures and Microsystems", <i>Topics in Current Chemistry</i> , Vol. 194, <i>Microsystem Technology in Chemistry and Life Sciences</i> , Springer Verlag, Berlin Heidelberg 1998, pages 1-20.
	Jean SCHULZE et al., "Compact Self-Aligning Assemblies with Refractive Microlens Arrays Made by Contactless Embossing", <i>SPIE</i> , Vol. 3289, pages 22-32.
CL	Thierry CORMAN et al., "Low-Pressure-Encapsulated Resonant Structures with Integrated Electrodes for Electrostatic Excitation and Capacitive Detection", <i>Sensors and Actuators A</i> 66, 1998, pages 160-166.
Examiner Signature	Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, D.C. 20231.